

1746 *SAH*
2
4-8-02

TRANSMITTAL OF FORMAL DRAWINGS

Docket No.
FIS920000409UST

In Re Application Of: MICHAEL R. SIEVERS, ET AL.

Serial No.
09/887,791

Filing Date
June 22, 2001

Batch No.

Examiner
Ahmed

Art Unit
1746/1765

Invention: FOCUSED ION BEAM PROCESS FOR REMOVAL OF COPPER



Address to:
Assistant Commissioner for Patents
Washington, D.C. 20231

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Transmitted herewith are:

two (2) sheets of formal drawing(s) for this application.

Each sheet of drawing indicates the identifying indicia suggested in 37 CFR Section 1.84(c) on the reverse side of the drawing.

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Peter R. Hagerty
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Dated: September 18, 2001

I certify that this document and attached formal drawings are being deposited on September 18, 2001 with the U.S. Postal Service as first class mail under 37 C.F.R. 1.8 and addressed to the Assistant Commissioner for Patents, Washington, D.C. 20231.

Marjorie R. Humes

Signature of Person Mailing Correspondence

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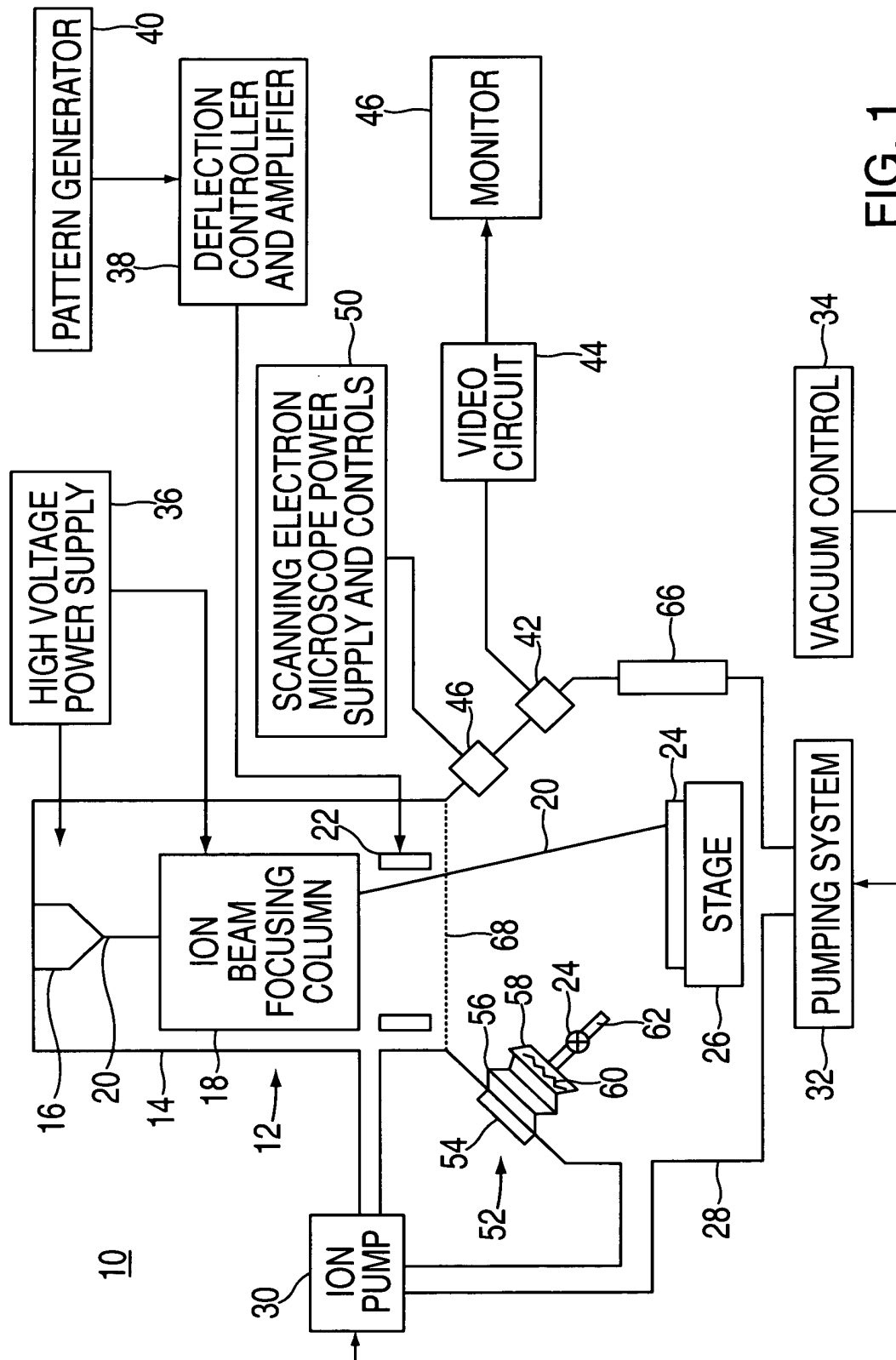
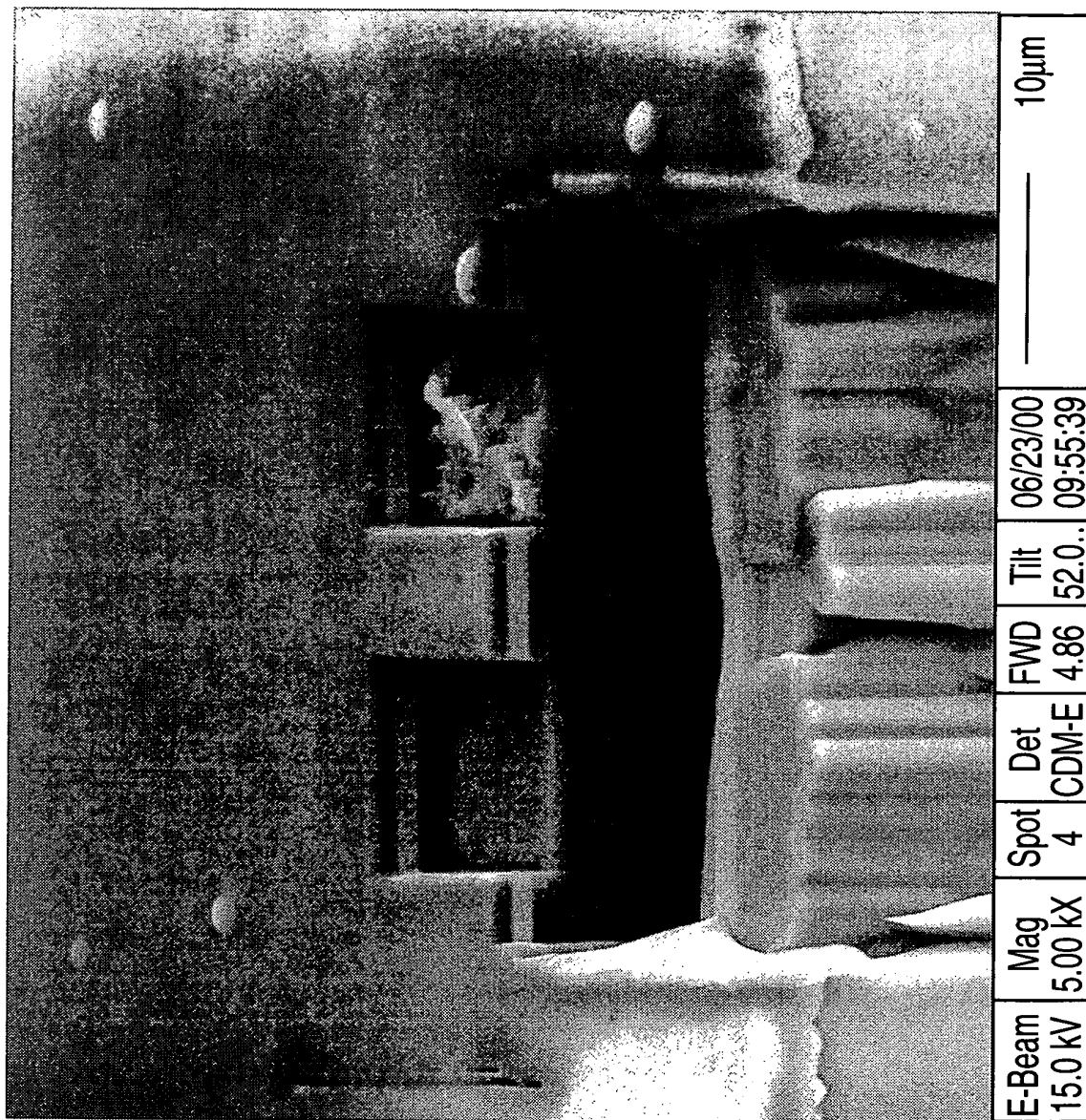


FIG. 1



E-Beam 15.0 kV	Mag 5.00 kX	Spot 4	Det CDM-E	FWD 4.86	Tilt 52.0..	06/23/00 09:55:39	10µm
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FIG. 2